

## Index

### **a**

aberration correctors 9, 13, 318, 322, 337  
 active pixel detectors (APS) 321  
 AC voltage 327–328  
 adsorption 196, 230, 241–243, 325  
 alignment protocol 337, 339  
 alloys 25, 50, 100, 132, 135, 165, 192, 239–241, 302  
 alternatives to free space approach 260–263  
 analytical TEM  
   chemical analysis  
     EDS 15–16  
     EELS 17–18  
     EFTEM 19–20  
     spectrum imaging (SI) 20  
 annealing metal hydroxides precipitates 99  
 anticontamination device 185, 202, 233–234  
 artificial intelligence age 308  
 Artificial neural network (ANN) 295  
 ATOMAI 299  
 atomic resolution imaging 47, 48, 67, 323  
 Atomic-Resolution Multi-Dimensional Transmission Electron Microscope 321  
 atomic resolution STEM images 96  
 auto-alignment algorithms 337  
 automation 307, 336–338, 340

autonomous experiments (AE) 308, 338–340  
 auxiliary microfabricated chips 324

### **b**

battery electrode materials 318  
 battery operations 3, 323  
 battery research 198–201, 323  
   closed liquid cell 200–201  
   open cell 199–200  
 Bayesian optimization 339  
 biasing 3, 27–28, 63, 84, 154, 161, 181–182, 184, 200, 318  
 butterfly' configuration 164

### **c**

carbon nanotube (CNT) growth 236–237  
 catalytic reactions 67, 215, 263, 318, 324, 330  
 charge density waves (CDW) 129  
 chromatic aberrations 149  
 citrination platform 299  
 closed cells  
   graphene cells 175–178  
   microfabricated window cell 178  
 closed liquid cell 200–201  
 closed vs. open cell configurations 244  
 clustering 294, 308  
 condenser lens 7, 46  
 controlled atmosphere 216  
 convolutional neural network (CNN) 295, 299, 301, 339

- core-shell structures 100–102
  - correlative approaches
    - electron and X-ray microscopies and spectroscopies 273–274
    - independent correlative measurements 278–279
    - portable reactor 274–278
    - TEM and SEM 270–272
  - cryo holders 117, 335
  - cryo samples 54, 119, 122, 323
  - cryo techniques 115, 124
  - cryo TEM 323, 324, 335
  - Crystal Ball Plus algorithm 302
  - cyclic voltammetry (CV) 166, 197
- d**
- darkfield images 321
  - data acquisition 10, 46, 185, 320, 326, 337
  - data management 291–292
  - data processing 285, 292–300, 321, 337
  - data transfer rate 307
  - deep convolutional neural networks (DCNNs) 339
  - deep kernel learning (DKL) 295, 299
  - DefectSegNet 299, 305
  - DefectTrack 299, 306
  - 1,2-dichlorobenzene (oDCB) 124
  - diffraction patterns 1, 11, 103, 131, 302–303, 321, 325
  - digital micrograph (DM) 287
  - direct electron detectors (DED) 10, 125, 317, 321, 328
  - direct heating holder 79
  - dislocation motion 93–94
  - dynamic transmission electron microscope (DTEM) 317–319, 327
- e**
- electrode-electrolyte interfaces 318, 323
  - electron beam 86–88, 324
    - effects 187, 229
    - translation control 332
  - electron-beam-induced deposition (EBID) 238–239
  - electron diffraction 11–12
  - electron-electron interactions 17, 325
  - electron energy-loss spectroscopy (EELS) 17–18, 217
  - electron optics 4, 18, 317
  - electron scattering and development 321
  - electron source or electron gun 5–6
  - electrons-sample interactions 4–5
  - electron transparent windows 84, 146, 174, 216
  - electropolishing 50, 51
  - electrostatic lens 329
  - embedded electrodes 166
  - energy-dispersive X-ray spectroscopy (EDS) 15, 318
  - energy materials 126–128
  - environmental microscopes (open cell)
    - differentially pumped TEM 224–227
    - ETEM combined with gas injection sample holder 223–224
  - environmental scanning transmission electron microscope (ESTEM) 318
  - environmental TEM (ETEM) 318, 327
  - eucentric height 7, 148
  - extended X-ray absorption fine structures (EXAFS) 255, 277
- f**
- Findable, Accessible, Interoperable, and Reusable (FAIR) 292
  - flow cells 157, 159–160, 178, 202
  - focused ion beam (FIB) 52–53, 221
  - 4D data cube 321
  - 4D-STEM 325
  - 4D-STEM nanobeam electron diffraction 322
  - fully convolutional networks (FCN) 295
  - furnace heating holders 79–82, 85
- g**
- galvanic replacement reactions 193–194
  - gas adsorption 234, 241–243, 325

- gas-cell holders 318, 330  
 benefits and limitations of 222–223  
 flow rate and pressure equilibrium 221–222  
 reactivity of gases and sample with windows 222
- gas-cell reactors 274
- gaseous environment 15, 57–59, 67, 77, 215, 218, 230, 234, 318, 333
- gas pressure and resolution 231–232
- Gatan imaging filter (GIF) 19, 217
- Gaussian Filter 287
- GC-MS system 223, 277, 330
- geometric distortions 332
- geometric phase analysis (GPA) technique 287
- graphene 175–178
- graphene sandwich superstructure (GSS) 177
- h**
- hexagonal boron nitride (hBN) 150, 196
- high-angle annular dark-field (HAADF) 14, 175
- high energy resolution EELS 89
- high resolution EELS 318
- holey or lacy 48
- holography  
 in-line holography 22  
 off-axis holography 22
- hybrid microscope 258–260
- hybrid pixelated array detectors (PAD) 321
- hydrogen evolution reaction 324
- HyperSpy 298, 299
- i**
- image and DP data base 308
- ImageNet 299–300, 339
- image processing  
 history of 285–289  
 progress in 290–291  
 techniques 317
- image segmentation 339
- image simulations  
 history of 285–286  
 progress for 289–290
- indentation 145, 244, 318
- independent component analysis (ICA) 293
- indirect heating holders  
 furnace 79–82  
 MEMS based heating holders 82–84
- inelastic mean-free path 18
- information recovery 308
- in-line Holography 22
- in situ cryo-TEM  
 benefits and limitations 137–138  
 biology 122  
 cooling 121–122  
 correlative in-situ experiments at low temperature  
 magnetic field 136–137  
 mechanical testing 135–136  
 historical perspective 116  
 materials science 122  
 mitigating radiation damage  
 energy materials 126–128  
 MOF and zeolites structure 125–126  
 polymers structure 124–158  
 quantum and 2-D materials 129–131  
 reactions in liquids 128–129  
 phase transformations below RT 132  
 physical science 122  
 reduced radiation damage 122  
 specimen design and preparation 119–121  
 specimen holder design and function 116–119
- in-situ gas-solid interactions  
 anticontamination device 233–234  
 applications  
 carbon nanotube (CNT) growth 236–237  
 electron-beam-induced deposition (EBID) 238–239  
 gas adsorption 241–243

- in-situ gas-solid interactions (*contd.*)
  - gas environment on catalyst
    - nanoparticles 234–235
    - nanowire growth 237–238
    - REDOX reactions 239–241
  - benefits and limitations 243–244
  - electron beam effects 229–231
  - environmental microscopes (open cell) 223–227
  - example 229
  - gas manifold design and construction 227–228
  - gas pressure and resolution 231–232
  - historical perspective 215–218
  - sample temperature and cell pressure 232–233
  - window holders
    - Browning's group 220
    - gas-cell holders 221–223
    - incorporation of other stimuli 221
    - SiN<sub>x</sub> windows 219
    - specimen design and preparation 221
    - windowed E-cells or nano-reactors 219
- in-situ heating
  - direct heating holder 79
  - dislocation motion 93–94
  - experimental considerations
    - electron beam 86–88
    - general 84–86
    - sample temperature at nanoscale 88–90
    - specimen design and selection 90–91
    - thermal drift 91–92
  - history 78
  - indirect heating holders
    - furnace 79–82
    - MEMS based heating holders 82–84
  - limitations and possibilities 105–106
  - nucleation, precipitation, and crystallization 94–96
  - sintering 98–100
  - thermal stability of materials
    - alloys 100
    - core-shell structures 100–102
    - materials synthesis 104–105
    - phase transformation 102–104
    - 2-D materials 102
- in-situ solid-liquid interactions
  - applications
    - battery research 198–201
    - corrosion/oxidation 192–193
    - galvanic replacement reactions 193–194
    - growth of core-shell nanoparticles 194–195
    - nucleation and growth of nanoparticles 190–192
    - quantitative electrochemical measurements 197–198
    - soft nanomaterials analyzed 195–197
  - closed cells
    - graphene cells 175–178
    - limitations of 178
    - microfabricated window cell 178
  - data acquisition 185
  - electrochemical cell, biasing 181–182
  - electron beam effects 187–188
  - flow reactors, microfluidic design 178–181
  - heating in liquids 182–184
  - historical perspective 173
  - interaction of sample with windows 189–190
  - limitations 201–202
  - sample loading 185–187
  - specimen design and preparation 184–185
  - windows bulging 188–189
- in-situ TEM 318
  - advantages 3
  - applications of quantitative data
    - catalysis 67
    - physical and materials science 66–67
  - development or modification of 47

- electrical, mechanical, radiation and magnetization 44
  - electron beam effects 55–56
  - experiments using other stimuli 63
  - functioning and applications of 24
  - grid and support material
    - reactivity of gasses/liquids with the TEM holder parts 59–60
    - reactivity of liquids with the windows 59
    - reactivity of TEM Grids in gaseous environment 58–59
    - reactivity of TEM grids upon heating 57–58
  - growth of GaN nanowires using ETEM 63–64
  - liquid cell experiments 62–63
  - microscope selection
    - image acquisition system and detectors 46–47
    - operating voltage 45–46
    - TEM/STEM and pole-piece gap 46
  - purity of gasses 60–62
  - specimen design and preparation
    - cryo sample preparation 54–55
    - direct dispersion 48–49
    - electropolishing 50
    - focused ion beam (FIB) 52–53
    - mechanical and ion milling 50–52
    - sintering pallets 49–50
    - tripod polishing 54
    - ultramicrotomy 50
  - stimulus and technique selection 44–45
  - ionic liquids 174, 199, 323
  - isopropanol (IPA) 177
  - isothermal sublimation of Ag nanocubes 89
- j**
- Johnson-Mehl-Avrami-Kolmogorov (JMAK) equation 67, 96
  - Joint Automated Repository for Various Integrated Simulations (JARVIS) 300
- l**
- Lab-in-Gap' dynamic microscope 321
  - lab on a chip 145, 219
  - laser alignment 269
  - lens aberrations 7–9, 13
  - lenses 7
  - LiberTEM 299
  - light induced superconductivity 321
  - Li ion batteries 126, 199, 201, 323, 339
  - linear/non-linear dimensionality reduction 339
  - liquid cell experiments 62–63
  - liquid cell holders 128, 318
  - liquid cell TEM (LC-TEM) 173
  - liquid-phase TEM (LP-TEM) 173
  - lithium dendrites 323
  - load-deflection behavior 151
  - Lorentz microscopy 20–22, 29
  - low vapor chemical vapor deposition (LPCVD) 155
- m**
- machine learning 322
    - limitation 309
    - motivation 296–298
    - supervised ML 294–296
    - unsupervised ML 293–294
  - magnetization 28–29, 318
  - materials community 215
  - Materials Genome Initiative 321
  - materials synthesis 104–105
  - MATLAB 289, 290, 295
  - matminer 300
  - mean filter 287
  - mechanical and ion milling 50–52
  - mechanical testing observations 335
  - metal-organic-frameworks (MOFs) 125–126
  - microchip fabrication process 154
  - microchips 85
  - microchips or chips 82
  - microelectromechanical systems (MEMS) 175, 218
    - based cryo-holder 118

- microelectromechanical systems (MEMS) (*contd.*)
    - based gas microreactor 324
    - based heating holders 82–84
  - microfabricated chip 159, 202, 274, 276, 277, 333
  - microfabricated device 333
  - microfabricated Si chip 333
  - microfabricated window-cell (microchips)
    - advantage 154
    - flow cells 159–160
    - incorporation of other stimuli 161–162
    - microchip fabrication process 154
    - microsphere ball lenses 154
    - monolithic microchips 162–163
    - SiNx windows 154
    - static cells 157–159
  - micromachining 167
  - microreactor 274, 276, 324, 325
  - micro-scale in-situ characterization techniques 255
  - microscope goniometer readout 336
  - mimics laser induced stroboscopic electron generation 327
  - modern TEM
    - aberration correctors 9
    - electron source or electron gun 5–6
    - lens aberrations 7–9
    - lenses 7
  - monochromated electron source 317, 318
  - monolithic liquid cell 333, 335
  - monolithic microchips 162–163
  - multimodal approaches 187, 256, 269, 335
  - multimodal measurements 322
  - multimodal microscopy
    - alternatives to free space approach 260–263
    - hybrid microscope 258–260
    - laser alignment 269
    - parallel ion electron spectrometry (PIES) 257–258
    - photon (PL or CL) 263
    - through sample chamber port 263–264
    - through sample holder 264–269
- n**
- nano-aquarium 166
  - nanofactory 166, 268
  - nanowire growth 237–238
  - neural networks 294, 295, 301, 322
  - Nion Swift 299
  - noise reduction 300–301
  - non-negative matrix factorization (NMF) 293
- o**
- objective lens 7, 9, 11, 13, 21, 29, 46, 329
  - off-axis holography 22
  - one-class support vector machine (OCSVM) 304
  - open cell 199–200
  - open circuit potential (OCP) 165
  - operating voltage 30, 45–46, 106, 231
  - original closed cells 175
  - oxidative dissolution mechanism of Pd nanoparticles 191
- p**
- parallel ion electron spectrometry (PIES) 257–258, 319, 327
  - periodic lattice distortion (PLD) 129
  - phase locked images 327
  - phase transformation 102–104
  - picometer image resolution 322
  - pixelated detectors 318
  - plug flow reactor 324
  - plunge freezing 119
  - pole-piece gap 331, 332
  - poly(3-hexylthiophene) 124
  - polymeric materials 324
  - polymethyl methacrylate (PMMA) 155
  - potentiodynamic polarization 165
  - principal component analysis (PCA) 293
  - projector or magnifying lens 7
  - protective layer 155

Protochips 165, 292  
 ptychography 325  
 pulse signal 327  
 py4DSTEM 298  
 Python 289, 290, 337  
 PyTorch 299  
 Pyxem 298

## q

quantitative electrochemical  
   measurements 197–198  
 quantitative parameters 339  
 quantum coherence 325  
 quantum computing 325  
 quantum confinement 325, 326  
 quantum dots 326  
 quantum fluctuations 325  
 quantum materials 325

## r

REDOX reactions 239–241  
 reinforcement learning (RL) 337  
 research groups 327

## s

sample loading 185–187  
 scanning transmission electron  
   microscope (STEM) 14  
 scikit-learn 299  
 signal to noise ratio (SNR) 149  
 Si nanowires 60, 64, 237, 268, 323  
 single-layer graphene (SLG) 175  
 sintering 98  
   pallets 49–50  
 SiN<sub>x</sub> window 168  
 Smart EPU software 337  
 SnO<sub>2</sub> 323  
 sodium yttrium fluoride (NaYF<sub>4</sub>) 279  
 Soft Actor-Critic (SAC) algorithm 337  
 solid-electrolyte interface (SEI) 127  
 spatial resolution 330  
 spectrum imaging (SI) 20, 194, 293  
 speed direct electron cameras 318  
 spin-orbit coupling 325  
 Spotiton robot 119

static cells 157–159  
 stroboscopic TEM 317, 319  
 structure determination  
   applications 305–307  
   atomic column heights 305  
   diffraction pattern analysis  
     302–303  
   image analysis 303–305  
 supervised ML 294–296

## t

TEM holders  
   design philosophy 146–148  
   historical perspective 146  
   modified window holders 166  
     combination 166  
     microchips for commercial holder  
       164–166  
     non-window cell holder to  
       incorporate other stimuli  
       166–167  
 windows  
   image resolution thickness and  
     material properties 149–150  
   inert or corrosion resistant  
     153–154  
   microfabricated window-cell  
     (microchips) 154–157  
   pressure difference tolerance  
     151–153  
   strength and flexibility 150–151  
 TensorFlow 299  
 thermal drift 91–92  
 thermal stability of materials  
   alloys 100  
   core-shell structures 100–102  
   materials synthesis 104–105  
   phase transformation 102–104  
   2-D materials 102  
 thermocouple 59, 78, 85, 88, 89, 118  
 Thermo Fisher Scientific 337  
 time resolution 10, 23, 30, 317, 332  
 Top Hat filter 287  
 transition metal dichalcogenides (TMD)  
   131

- transmission electron microscope (TEM)
    - analytical 14–20
    - automation 336–338
    - biasing 27–28
    - characterization 2
    - data acquisition systems 9–10
    - electron diffraction 11–12
    - electrons-sample interactions 4–5
    - historical perspective 4
    - Holography 22
    - imaging modes 12–13
    - ion radiation/implantation 25–27
    - Lorentz microscopy 20–22
    - magnetization 28–29
    - mechanical testing 25
    - modern 5–9
    - potential limitations and cautions 29–30
    - sample chamber ports 336
    - UEM and DTEM 23–24
  - tri-*n*-octylphosphine (TOP) 191
  - tripod polishing 54
  - tuning fork-based IR detector 332
  - 2-D materials 102
- u**
- ultrafast electron diffraction and microscopy 321
  - ultrafast electron microscopes (UEM) 23, 317–319, 327
  - ultramicrotomy 50, 54
  - unsupervised ML 293–294, 298
  - user adjustable pole-piece (UAP) 331
- w**
- water splitting 24, 195, 263, 324
  - wet cells 173
  - white lines 19, 93
  - window cells 148, 154, 157, 164, 166
  - windows bulging 188–189, 202









